

# Challenges in gravure and ink-jet printing of nano-colloidal inks

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University of New Mexico

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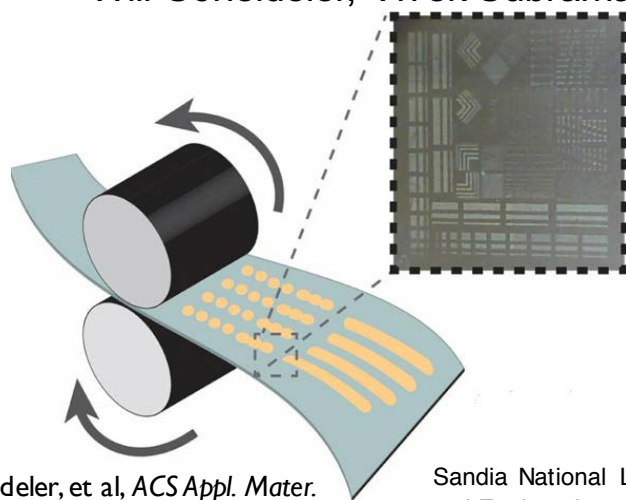
Sandia National Laboratories

## Contributions:

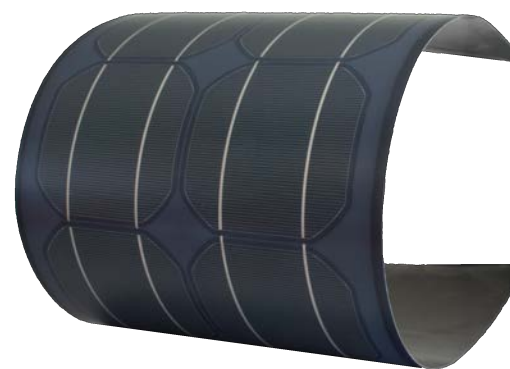
Kristianto Tjiptowidjojo, Robert Malakhov (UNM)

Nelson Bell, Adam Cook, Sandia National Laboratories

Will Scheideler, Vivek Subramanian, UC Berkeley



Scheideler, et al, ACS Appl. Mater. Interfaces, 2015



<http://solarindustrymag.com/midsummer-develops-sputtering-process-for-cigs-solar-cells-on-stainless-steel>

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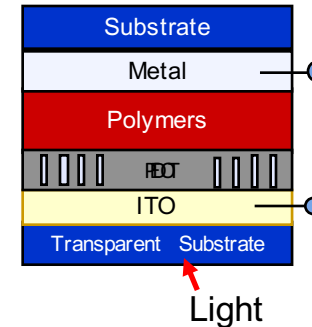




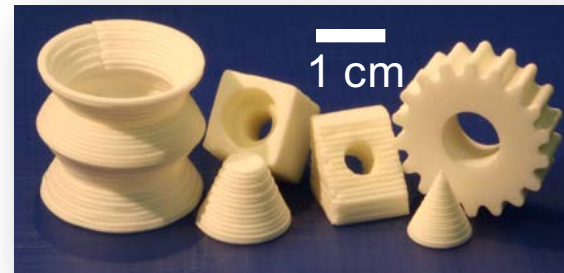
Why ink-based processing? – one example

# Particulate Inks for Energy, Computing/Sensing, Ceramic Piece Parts and more

Energy Storage/Generation Materials



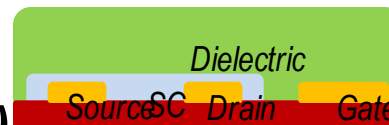
Ceramics and meta-materials



Flexible electronics

- Materials/devices for energy storage, generation, conversion, sensors needed in volume – **AM with physical template (viz. demands speed, R2R)!**
- Fully-dense ceramic piece parts and other specialized materials– **AM with digital template (e.g. demands design flexibility - direct write)**
- Printed electronics – packaging and logic devices **AM with digital and physical templates (demands materials flexibility and precision)**

Mobile computing





What is an “ink”?

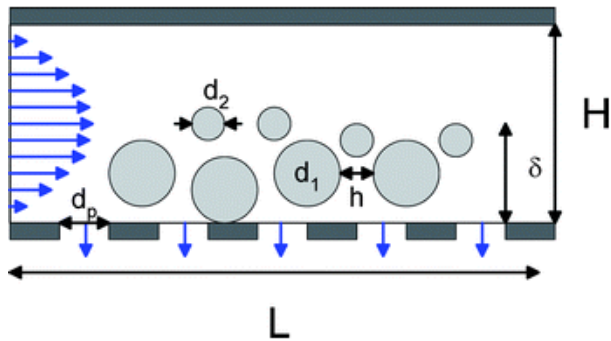
# Ink “generalization”

iNGk: a colored fluid used for writing, drawing, printing, or duplicating.

Simulations of confined suspension flow at multiple length scales†

R. G. M. van der Sman – *Soft Matter*, 2009

(5)



Mixture of particles and carrier fluid

- Particle size
- Particle size distribution
- Particle shape
- Particle material/mechanics
- Solvent/carrier rheology
- Particle loading

Ink “type”

Solution

- Dissolved species which undergo phase change upon deposition, e.g. Dye

Colloidal, nano-colloidal –

- Dispersions
  - Stabilized through long range molecular forces and short range thermal motion (brownian)

Suspensions

- Non-colloidal (>2-3 microns)
  - Dilute – settle out (sedimentation)
  - More Concentrated – sedimentation
  - Paste – viscous carrier and concentrated - stable

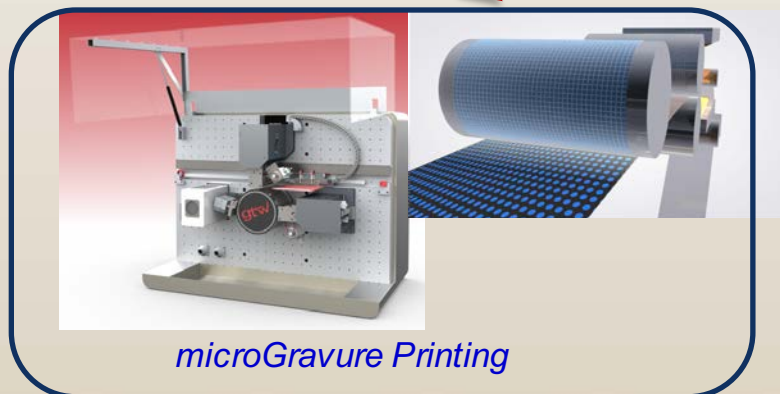
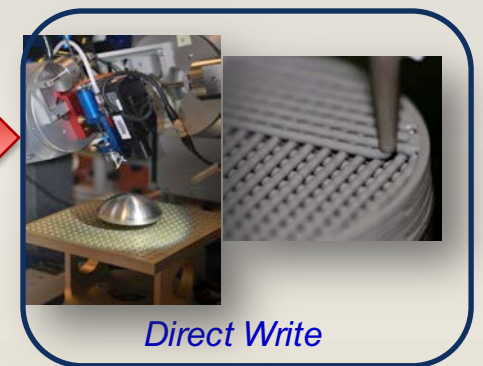
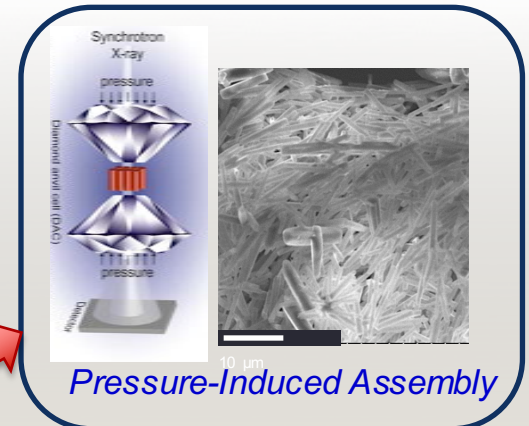
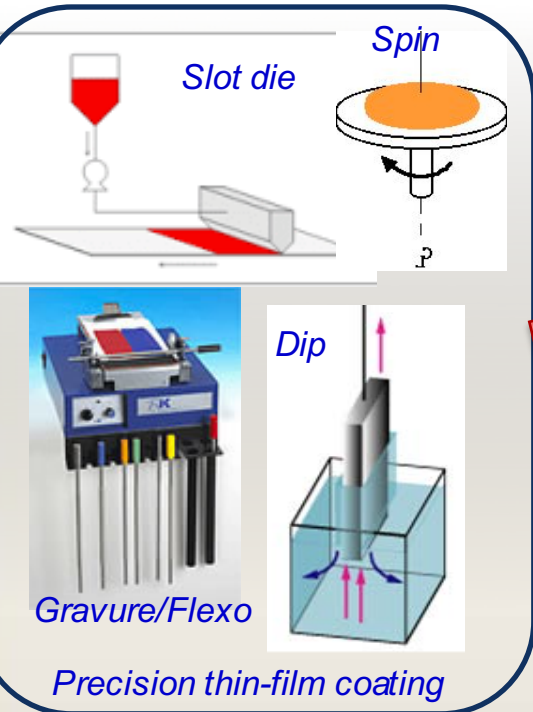
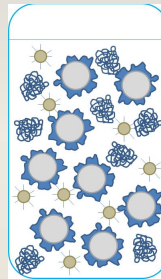
Dry Ink – e.g. toner (delivery through electrostatics)



# AML Materials Processing Routes

Particle effects in most of these ink processes have yet to be addressed with focused research

Chemistry -> Nanomaterials->Inks

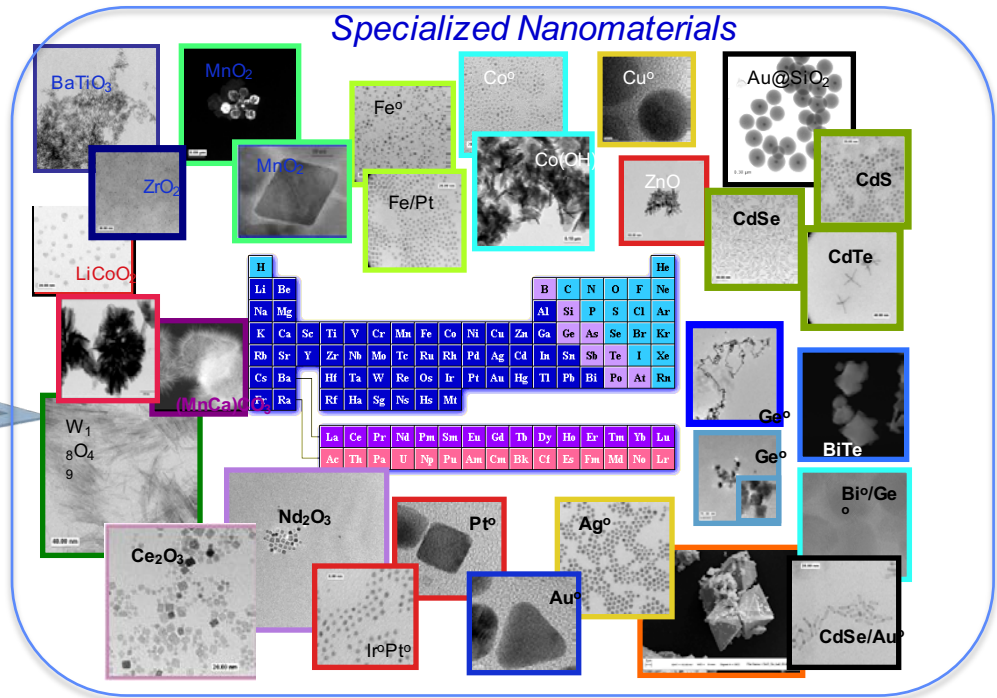
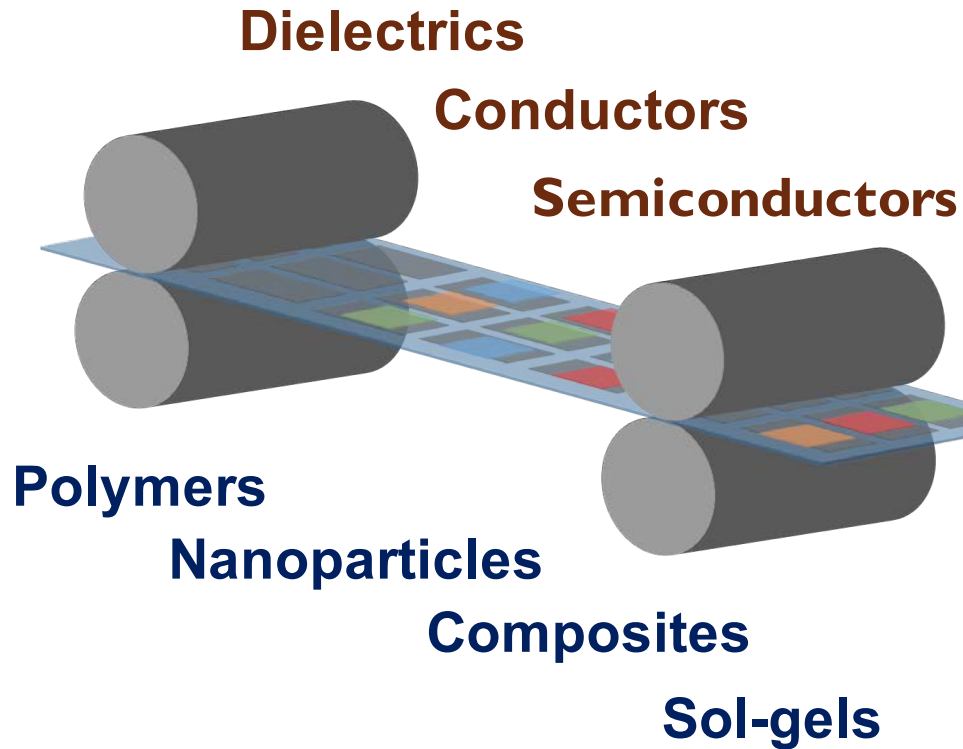




# Printing Inks Carry Functionality

The strong suit of printed systems is the integration of diverse materials

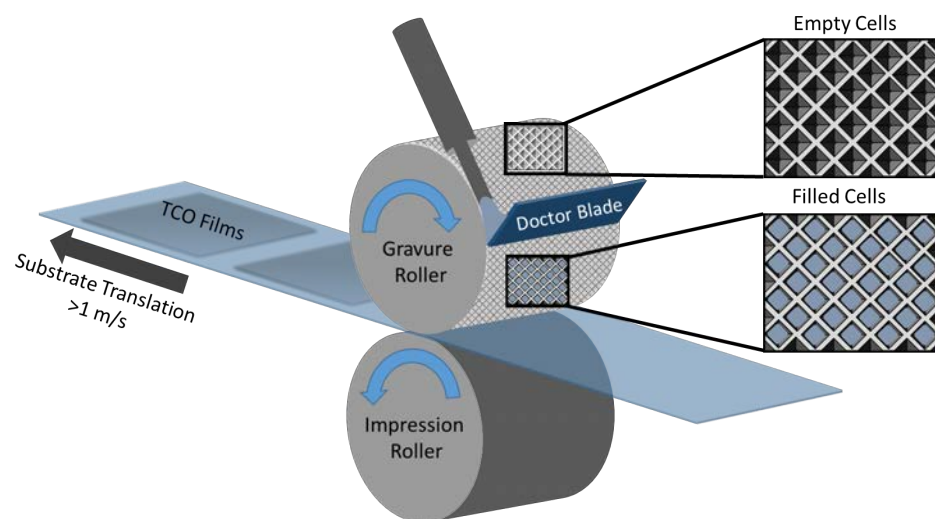
But process design can depend on these material selections.



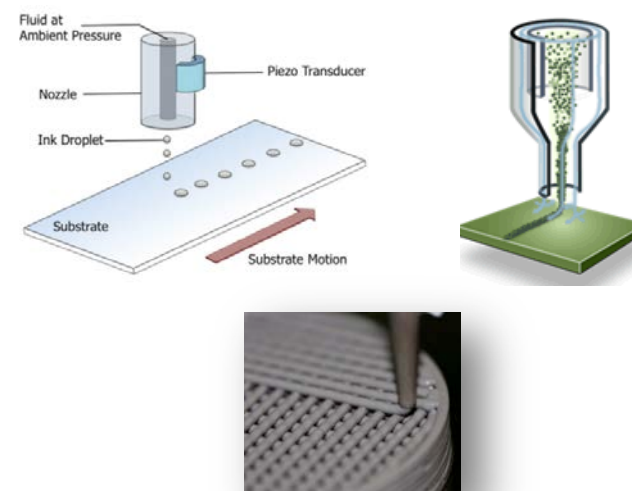


# Promising Ink-based printing routes

## Gravure/Flexographic Printing



## Direct Write (DoD, DW, Aerosol)



	Gravure	Direct write
<b>Resolution</b>	$< 5 \text{ } \mu\text{m}$	$< 30 \text{ } \mu\text{m}$
<b>Speed</b>	$1 \text{ m}^2/\text{s}$	$< 1 \text{ m}^2/\text{hr}$
<b>Ink Viscosity</b>	$1\text{-}500 \text{ cP}$	$1 \text{ cP} - 10^4 \text{ P}$
<b>Method</b>	Contact	Non-Contact

**Inkjet and gravure are complementary methods for low-cost fabrication**

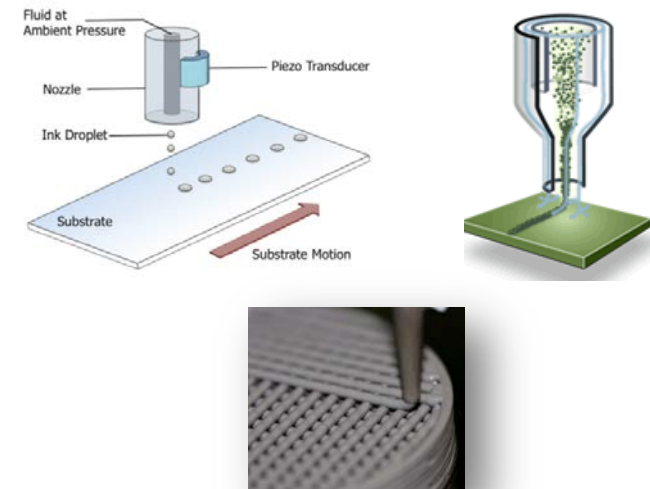


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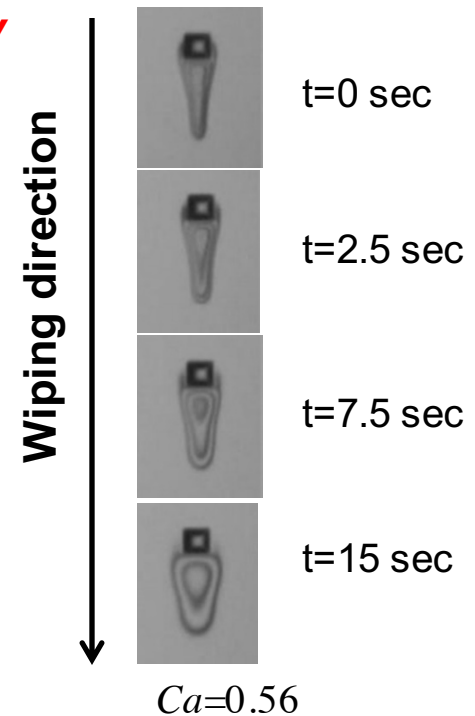
**Inkjet and gravure are complementary methods for low-cost fabrication**



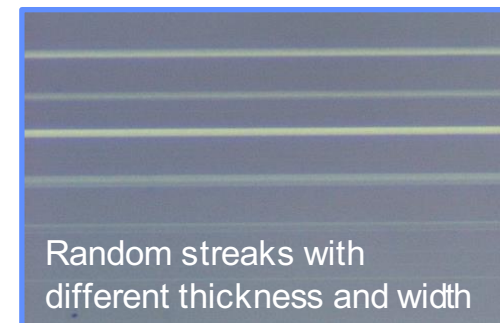
# Important experimental observations on particle effects in gravure printing

*Particles are both a blessing and curse: Material functionality through particle ink routes nearly limitless, BUT*

- **Bulk viscosity ( $f(\text{particles})$ ) undermines feature sharpness and size** — models have confirmed this
- **Abrasion likely heightens blade and proof wear, clogs nozzles.** More deliberate experiments and modeling should be undertaken
- **Residue increases with particle size, as does streaking artifacts.** Cutoff length scale exists.
- **Particle effects on ink transfer, filling, have not been studied at all,** experimentally and theoretically.
- Virtually no experimental or computationally/theoretical work on the **bulk rheology effects of particles in inks** (complex fluid behavior like **thixotropy** and **viscoelasticity**).
- **Particles are discrete until densified, sintered, etc.** Process-Structure-Property needs extensive theoretical and experimental attention

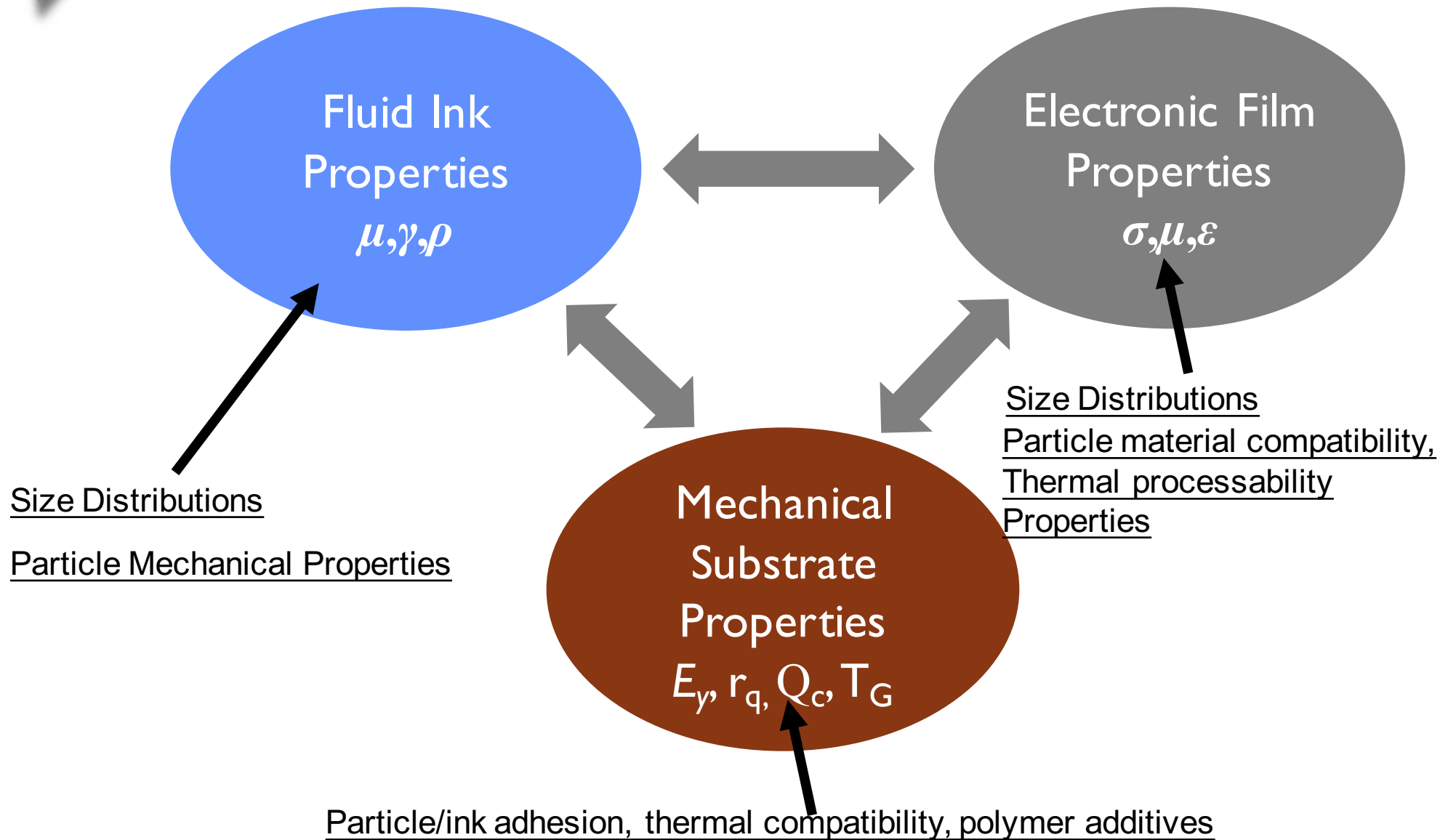


JS-B40G Inkjet Ink ~ 9cP





# Gravure/Ink-Jet Process science for ink-printing requires Co-Design



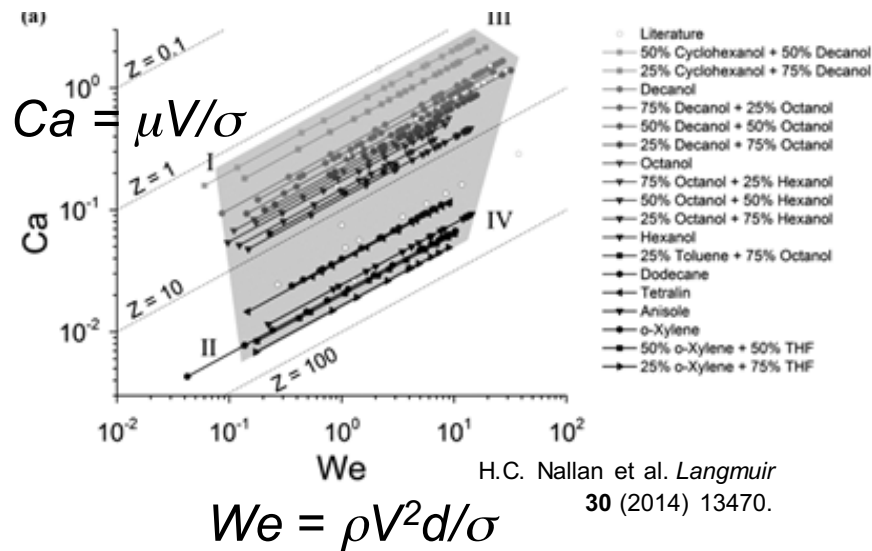
***Inks, printing processes, and devices require iterative codesign***



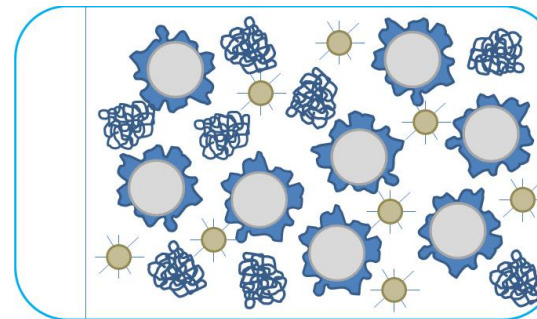
# Development of Ink Compositions for Printing

- ✓ Ink Systems are formed from multiple components: Solvents (s), wetting agents, soluble polymers or micelles, & nanoparticle(s)
- ✓ Control over viscosity, surface tension, drying rate, and wetting are required.

## A. Solvent compositions effects on printing window. B. Effective dispersion is critical for printing using DOD or gravure/flexo printers.



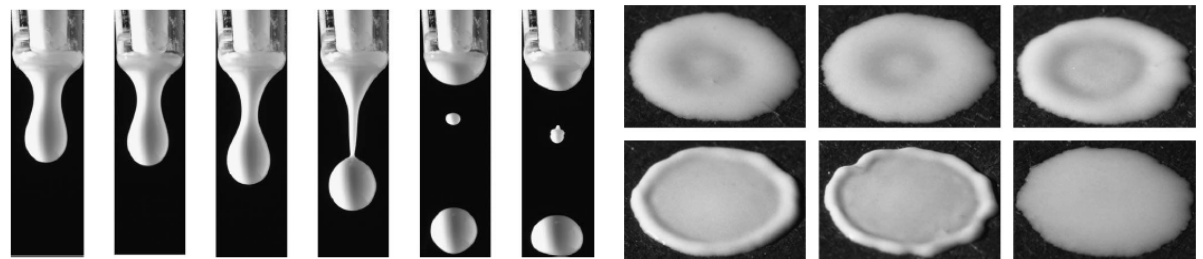
- Solids loading increased by proper dispersant choice, up to ~15-20%
- Surface tensions are low : between 15 – 40 mN/m
- Viscosity vary from 1-10 mPas.
- Surfactant concentrations tailored to surface area.



$$\mu_{rel} = \mu_{susp} / \mu_{sol} = (1 - \phi / \phi_m)^{-n}$$

## C. Adjust wetting and drying agents to minimize satellite drops and surface wetting concerns.

Dependent on surface interactions with substrate, and drying rate.



R. Guo et al. *JECerS* **23** (2003) 115-122.; X. Zhao, et al. *Ceram.Intl.* **29** (2003) 887-892; N. Ramakrishnan, et al. *J. Mat. Proc. Tech.* **169** (2005) 372-381.; P.S.R. Krishna Prasad et al. *J. Mat. Proc. Tech.* **176** (2006) 222-229.

**All experimental capabilities and SMEs exist at the AML!**



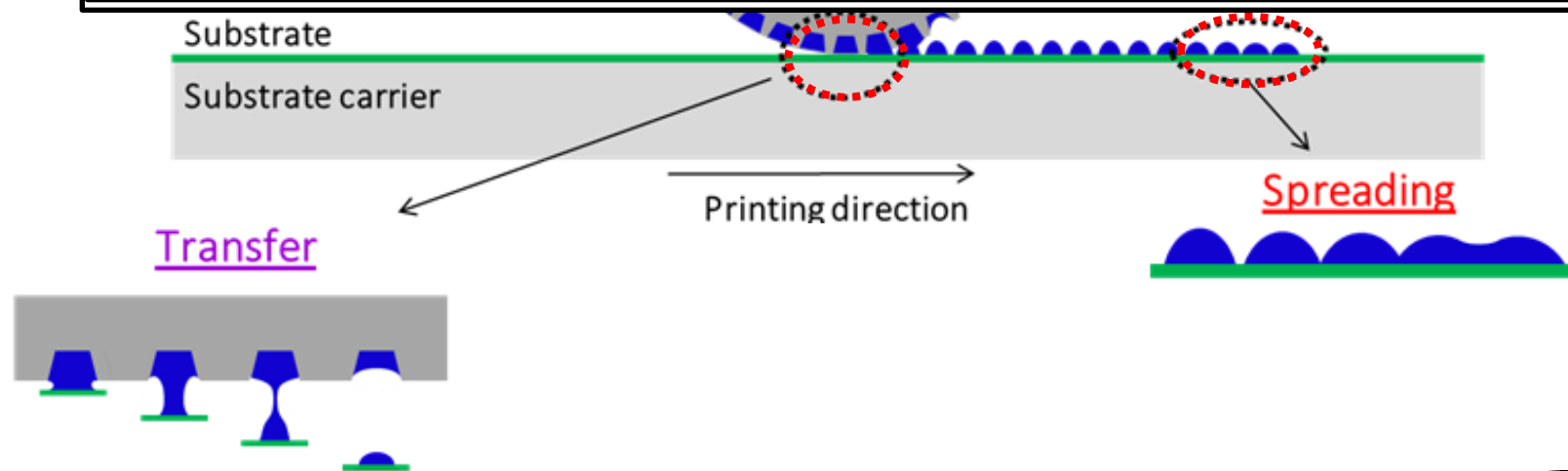
# Bring to bear Computational Mechanics: What we know and don't know...

Continuum Mechanics – 3D capillary hydrodynamic solvers

- Capable amenable to  $Ca < 1$  and various high  $0 < We < 100$ .
- Complex liquid rheology (VE, Yield-Stress, etc.) - **Particles**
- **Reduced order models for extreme geometries**

Continuum and discrete element solvers for consolidation, sintering–

- Solvent drying through porous media, consolidation (thermal, multiphase flow)
- Calendaring (thermal, mechanical, multiphase flow)
- **Sintering** (phase-change, reactive) - (Thermal, reactive, mechanical, fluid)

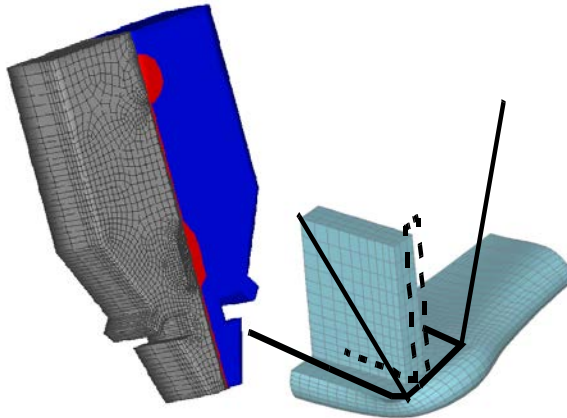
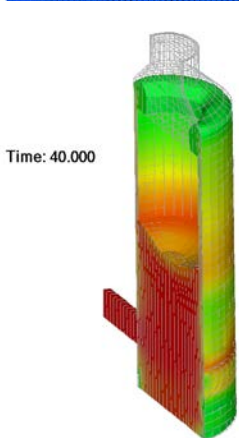
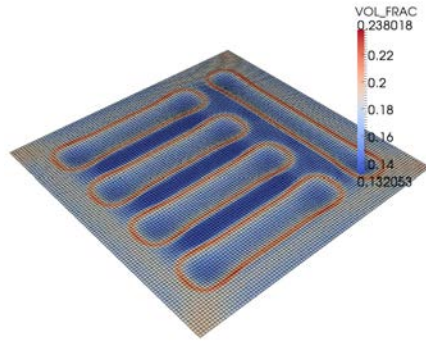
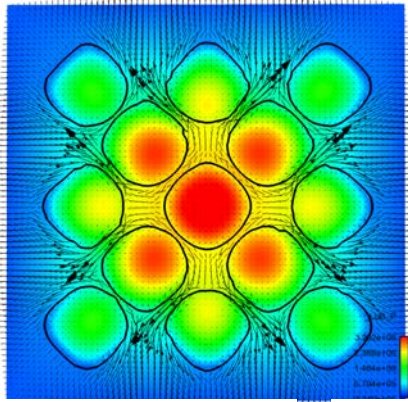






**2014 R&D 100 Award Winner**

## Research Group Capability: Goma 6.0



- Multiphysics *finite element* code, suitable for both *research* and *production*
- Fully-coupled *free* and moving *boundary* parameterization – ALE, Level Set, etc.
- Modular code; *easy to add equations* – currently has 170+ differential equations
- *Open source*! Available at <http://goma.github.io>
- *Goma 6.0. training* is available on regular basis

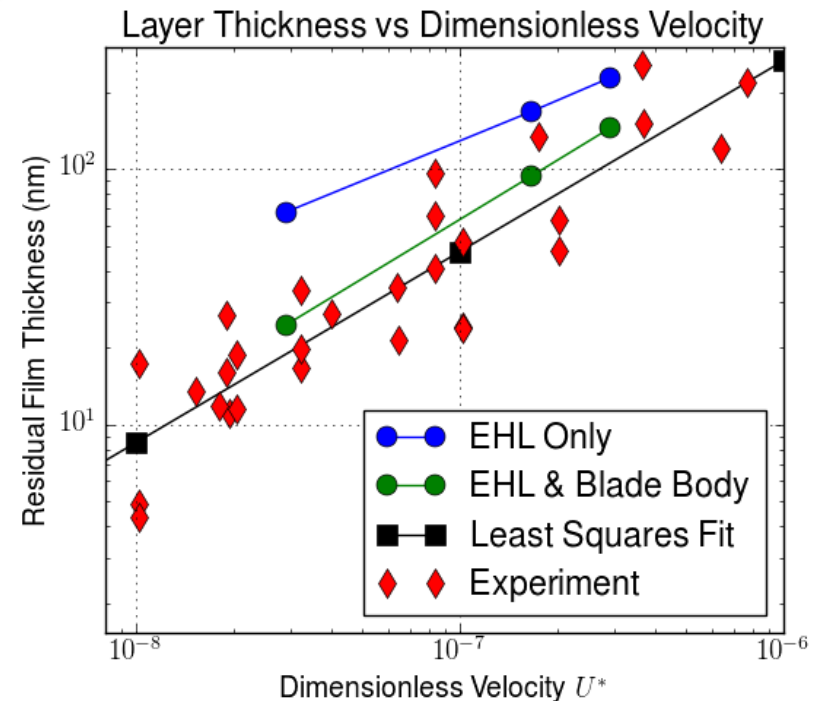
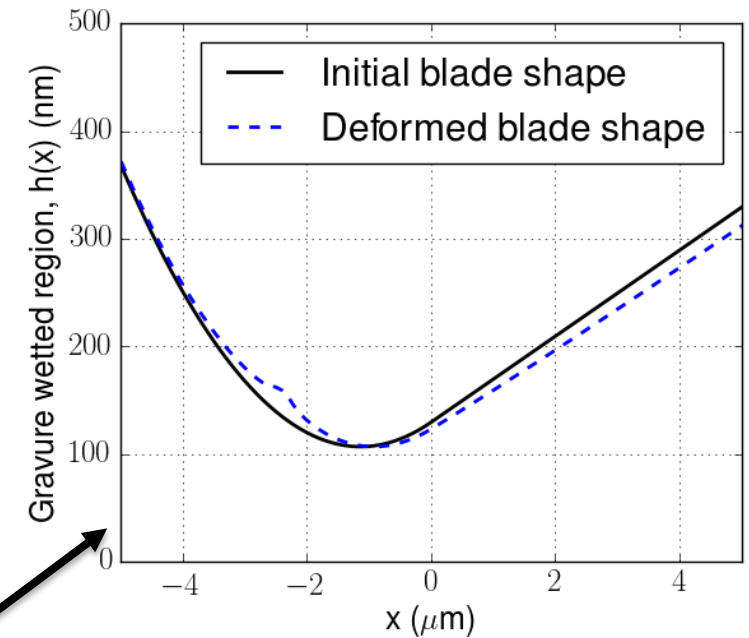
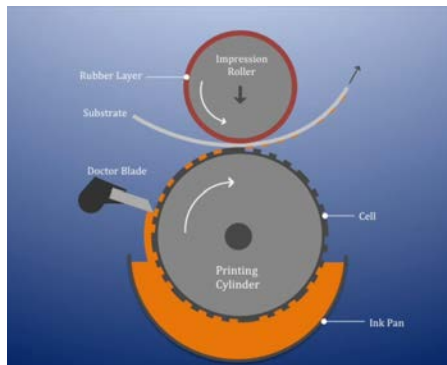
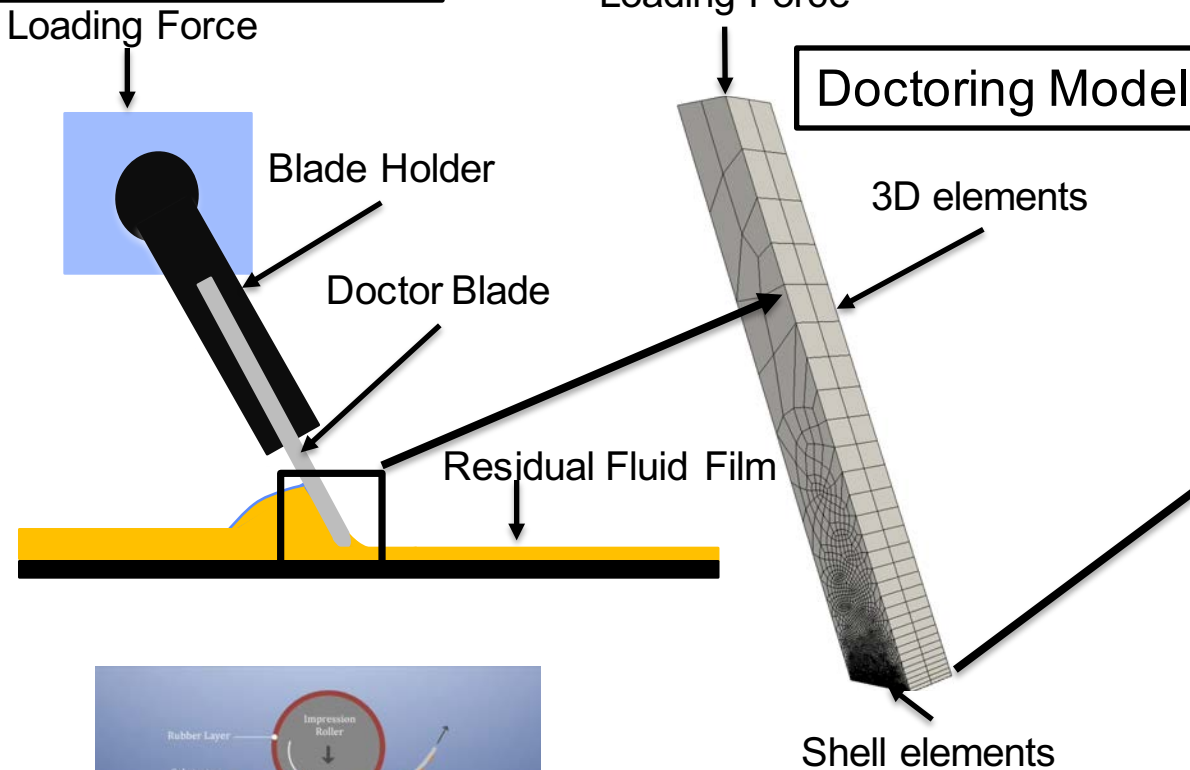
***Goma has been used successfully in coating manufacturing for 2 decades!***

*...Also a competency in LAMMPS for colloidal rheology and self/directed assembly*



# Doctoring in gravure printing *Ink printing routes*

## Doctoring process

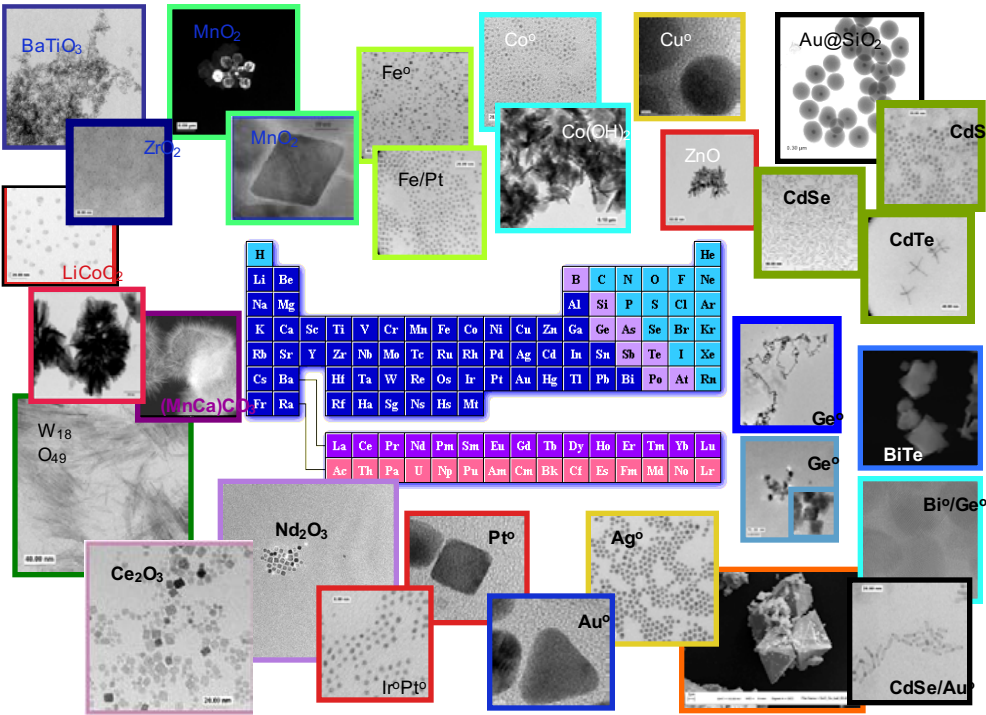




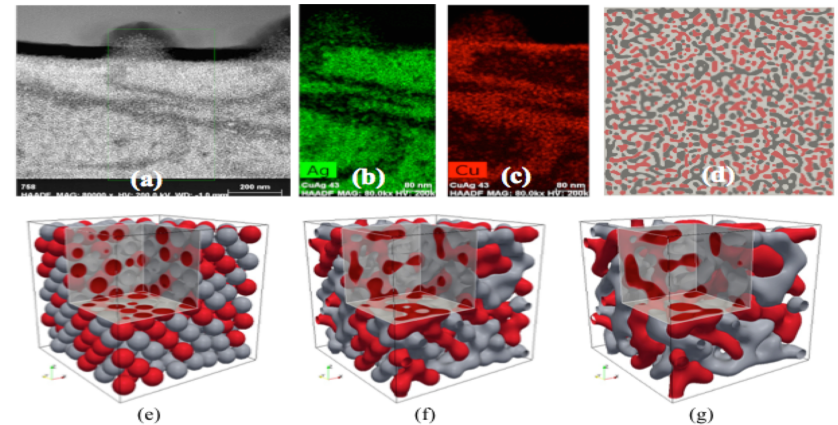
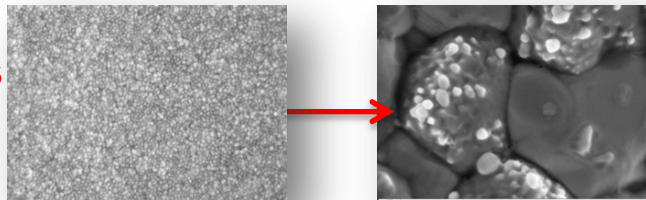


# Solidificati

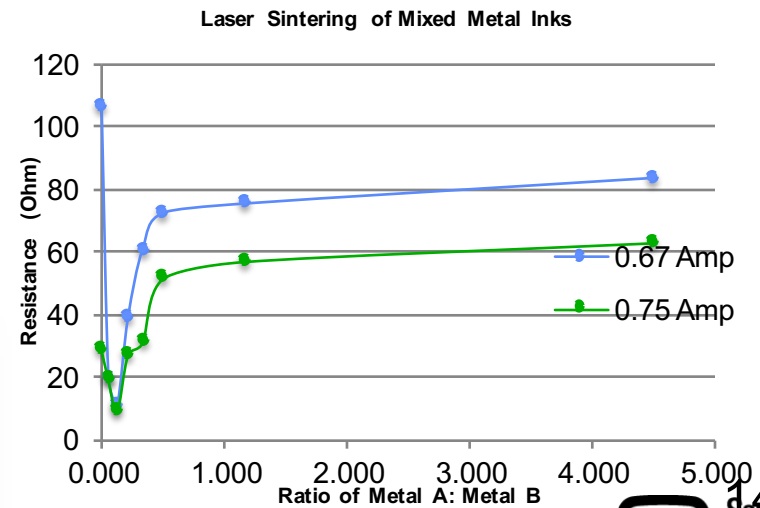
The development and study of tailored materials enable prototyping of functional components using Direct Write methods



# Curing metal inks changes functionality!



F. Abdeljawad, et al, A Diuse interface model of grain boundary faceting", *J. App. Phys.* 119, 235306 (2016)







# Sandia and Industrial Partnership for CAE tool development to assist ink design: The NanoParticle Flow Consortium (NPFC)

Comp. Part. Mech. (2014) 1:321–356  
DOI 10.1007/s40571-014-0007-6

## Particle dynamics modeling methods for colloid suspensions

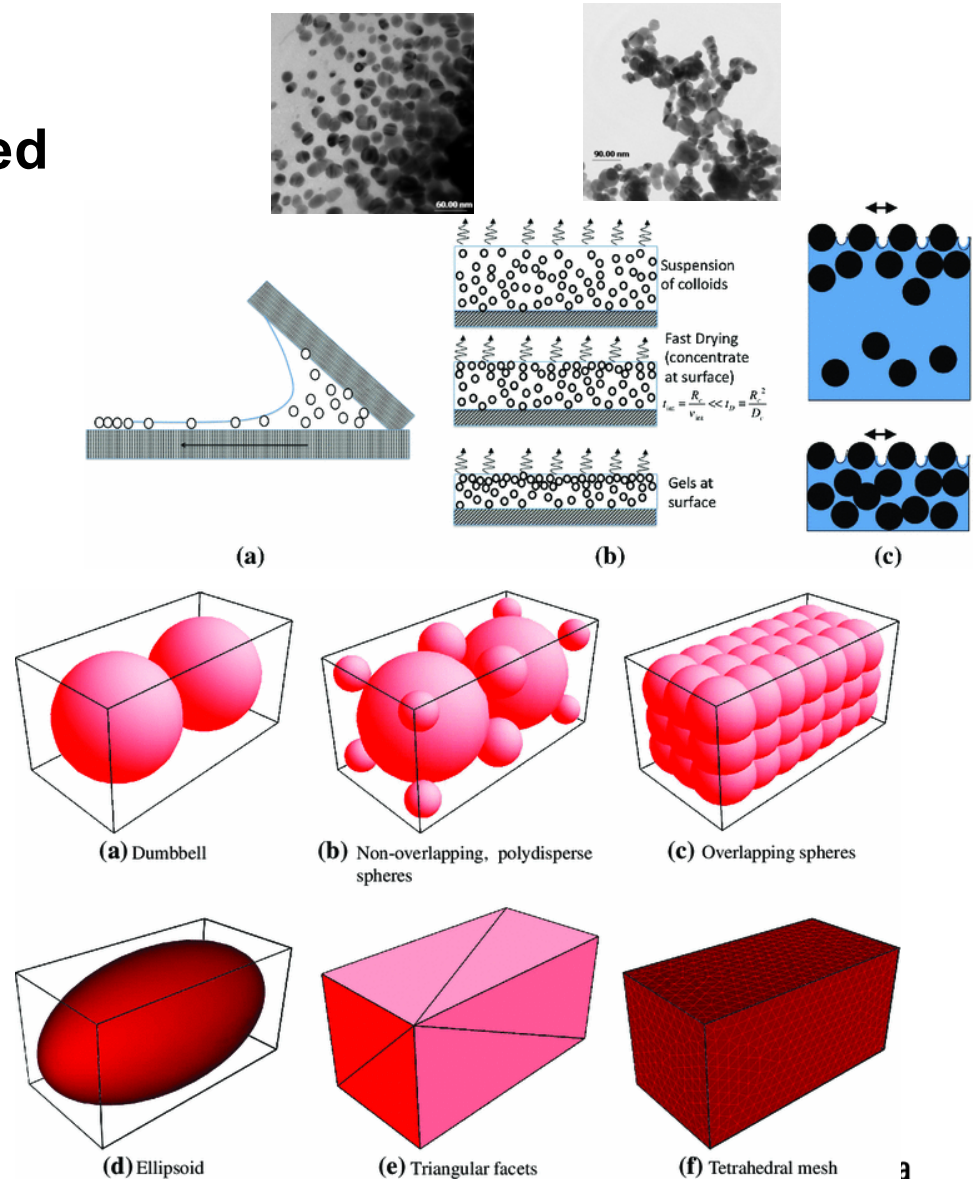
Dan S. Bolintineanu · Gary S. Grest ·  
Jeremy B. Lechman · Flint Pierce ·  
Steven J. Plimpton · P. Randall Schunk

	Explicit Solvents		Implicit Solvents
	DPD	MPCD	SD-based (FLD, BD)
PREDICTIVE ABILITIES FOR SIMPLE SUSPENSIONS OF SPHERICAL PARTICLES			
Diffusion and viscosity	Well-established, but minor challenges remain in accuracy/boundary conditions; large polydispersity ratios can be computationally challenging		Well-established, but large polydispersity ratios still problematic
Microstructure prediction	Finite size of DPD particles problematic at high volume fractions/close particle contact.	Depletion effects introduce artificial inter-particle interactions.	Excellent agreement with experimental data for simple systems.
Direct mapping to physical properties	Often difficult, not all properties can be achieved simultaneously. Inherently problematic due to low Schmidt numbers and high fluid compressibility.		Simple solvent properties (e.g. viscosity, temperature) are directly input.
ADVANCED CAPABILITIES			
Non-spherical particles	DPD-colloid coupling relies on centrosymmetric potential; problematic for general case	Minor challenges exist with regard to boundary conditions/accuracy	Some simple shapes tractable. Near-field only applicable to spheres, spheroids, or particles composed of spheres; crude approximations possible for far-field.
Non-Newtonian solvent rheology	Modified algorithms can achieve certain solvent rheological properties; mapping to exact given rheology difficult		No attempts reported; requires significant development (e.g. coupling to mesh-based continuum solvers (FEM/CFD))
Complex flow geometries	Minor challenges with regard to boundary conditions/collision detection.		Boundary condition development required for confined and flow through systems. Not suitable for arbitrary geometries.
Solvent removal (drying) and/or curing	Solvent can be readily removed to simulate drying. Capillary forces must be added. Viscosity cannot easily be adjusted during simulation.		Only simple slow drying models possible (e.g. moving wall). Capillary forces must be added. Solvent curing can be simulated by changing viscosity.



# Advanced Capability Requirements for DEM Methods

- Complications requiring advanced capabilities
- -Non-Newtonian solvents
- -Aspherical particles
- -Drying/solidification
- -Complex flow geometries
  - Confined
  - Extreme shear
  - FSI







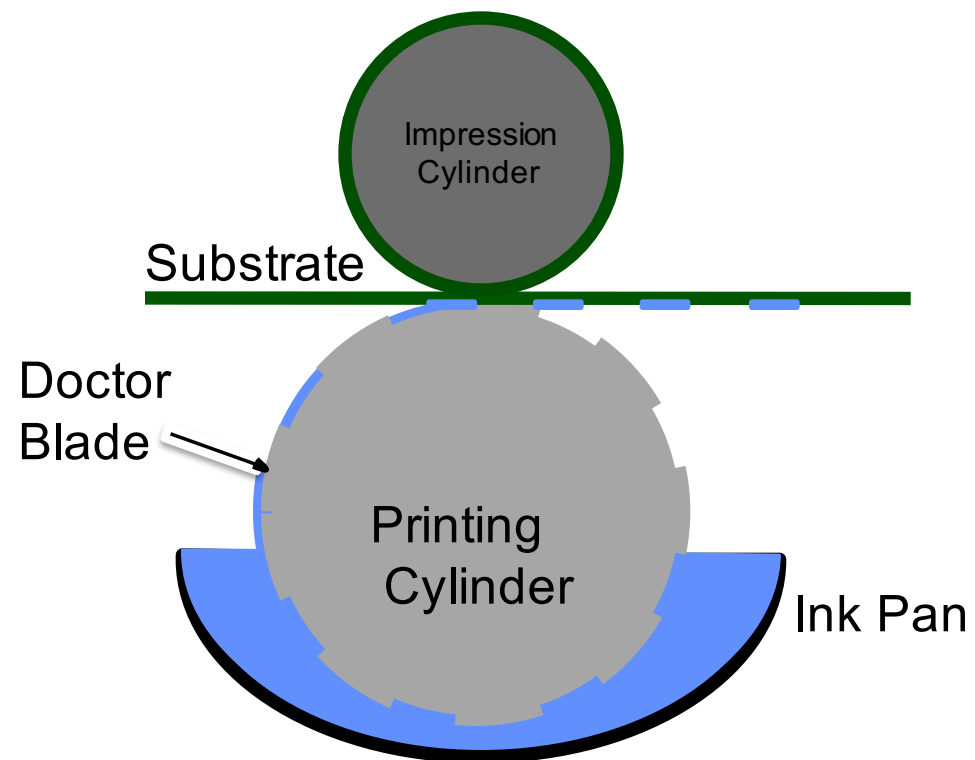
# Summary & Future Work

- Ink-based AM routes age-old, mature in an “Edisonian” sense
- Precision applications demand wider materials palette and colloidal materials
- Precision applications require ink-design, material properties, and substrate properties to be “co-designed” with the printing and solidification processes
- Physical barriers to higher throughput and smaller features are rooted in
  - Capillary hydrodynamics
  - Wetting and spreading
  - Structural mechanics (thin sheet)
  - Metrology (on-line/at-line)
  - Colloidal dispersion dynamics (rheology, wetting and spreading)
  - Solidification and microstructure
- Many outstanding problems in computational mechanics remain
  - DEM, Continuum, Phase-field



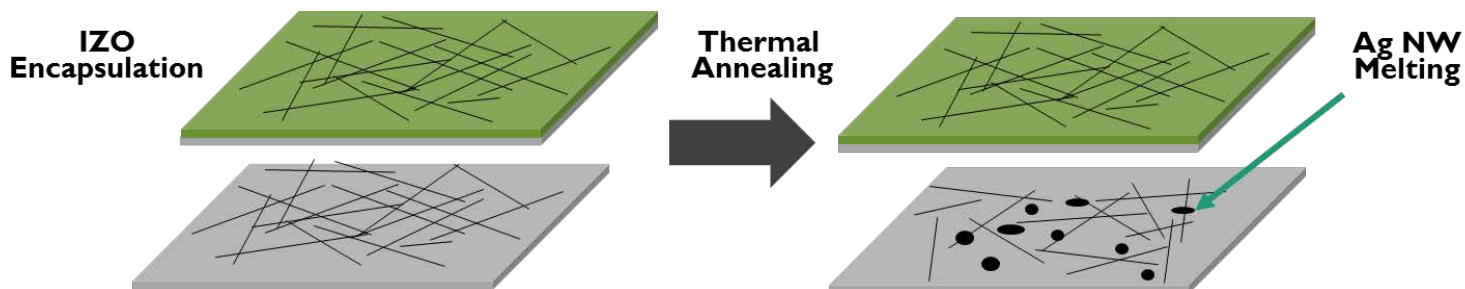
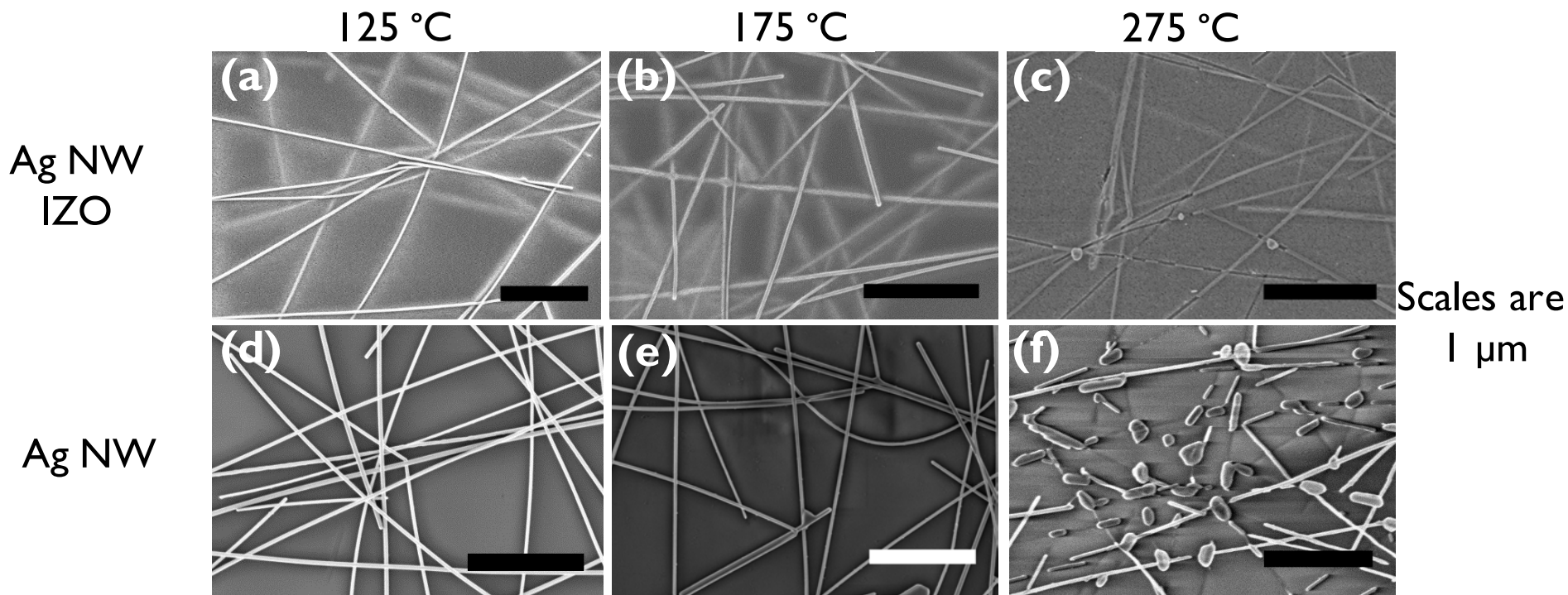


# BACKUPS





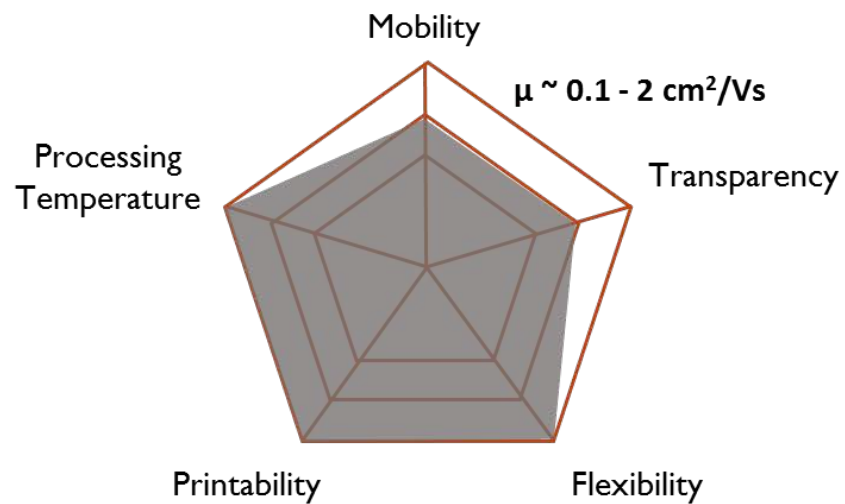
# Nanowire Hybrid Encapsulation



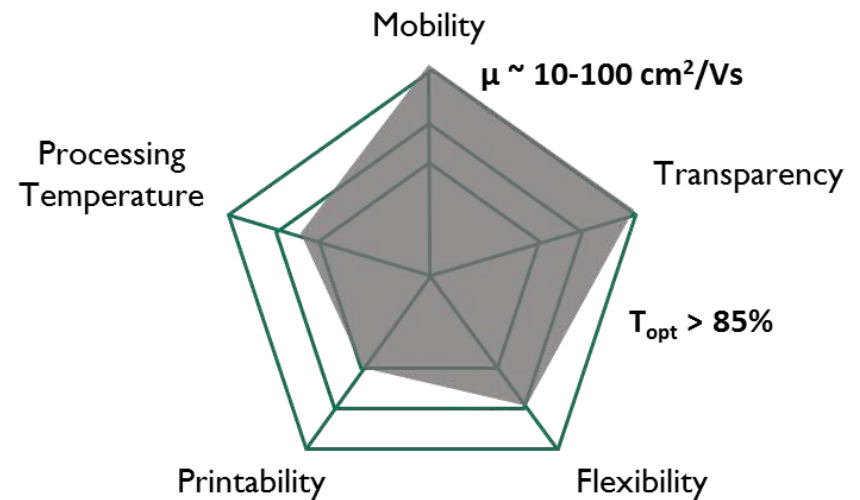


# High Performance Printed Transistor Materials

## Organics

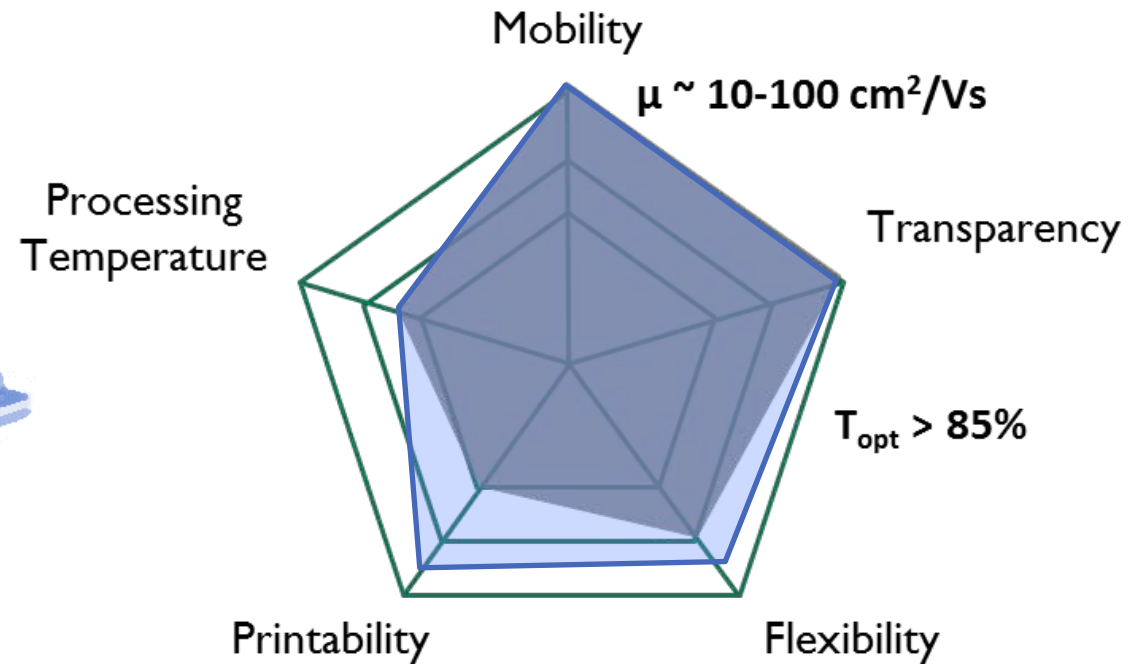
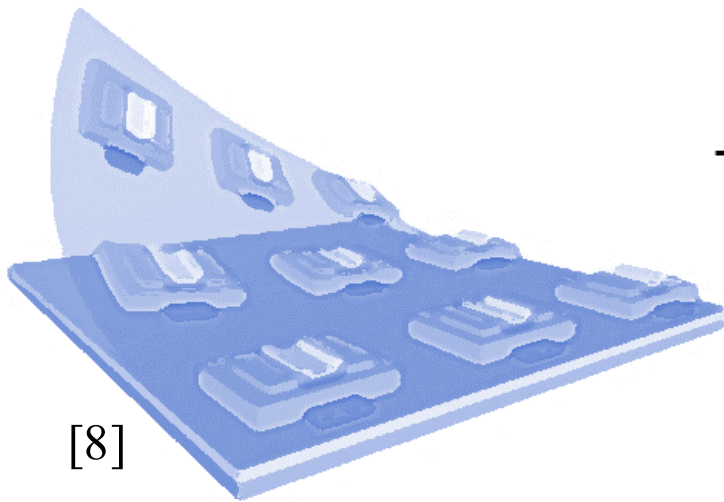


## Transparent Metal Oxides





# Limitations of Gravure Printed TCOs (Transparent conducting oxides)



**High Annealing  
Temperatures**

**Film Stress & Cracking**

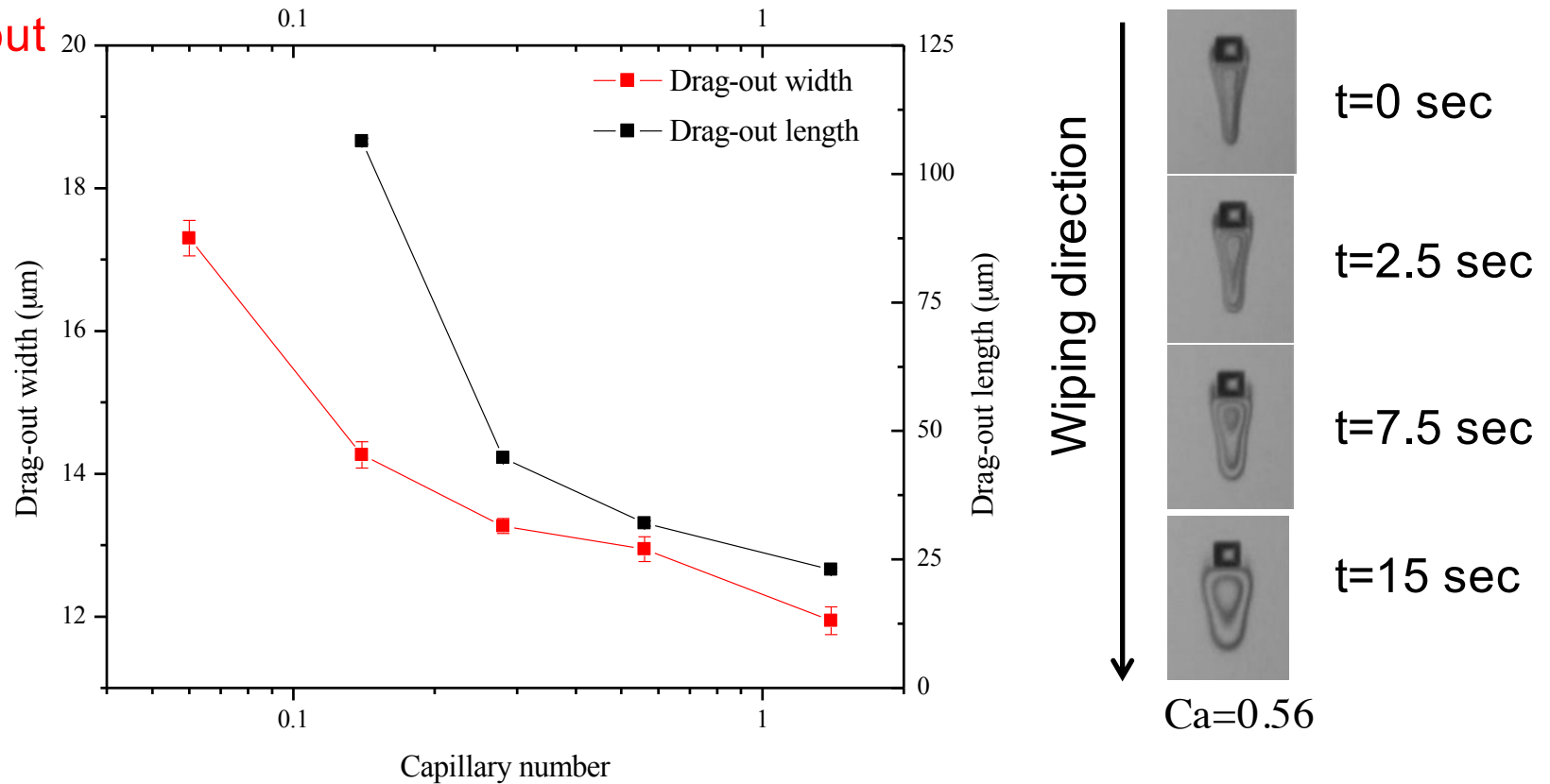
**Mechanics of Flexible  
Glass**

Low temperature compatible inks can solve these issues



# Single-Cell Dragout Tail Features

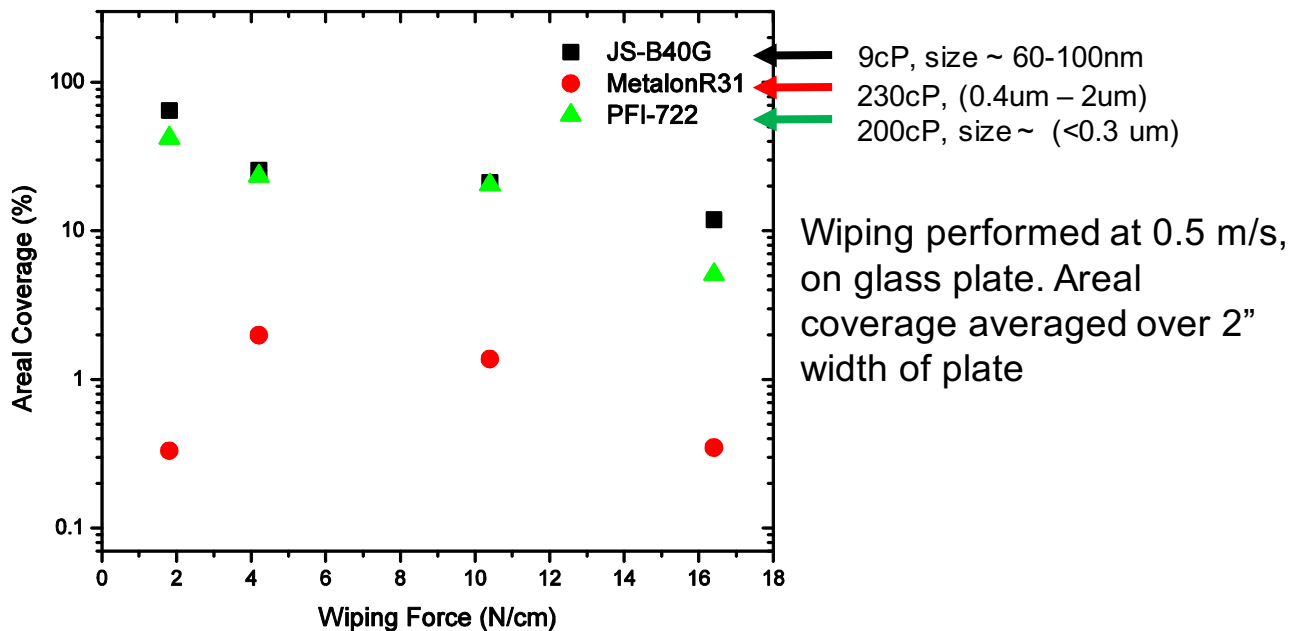
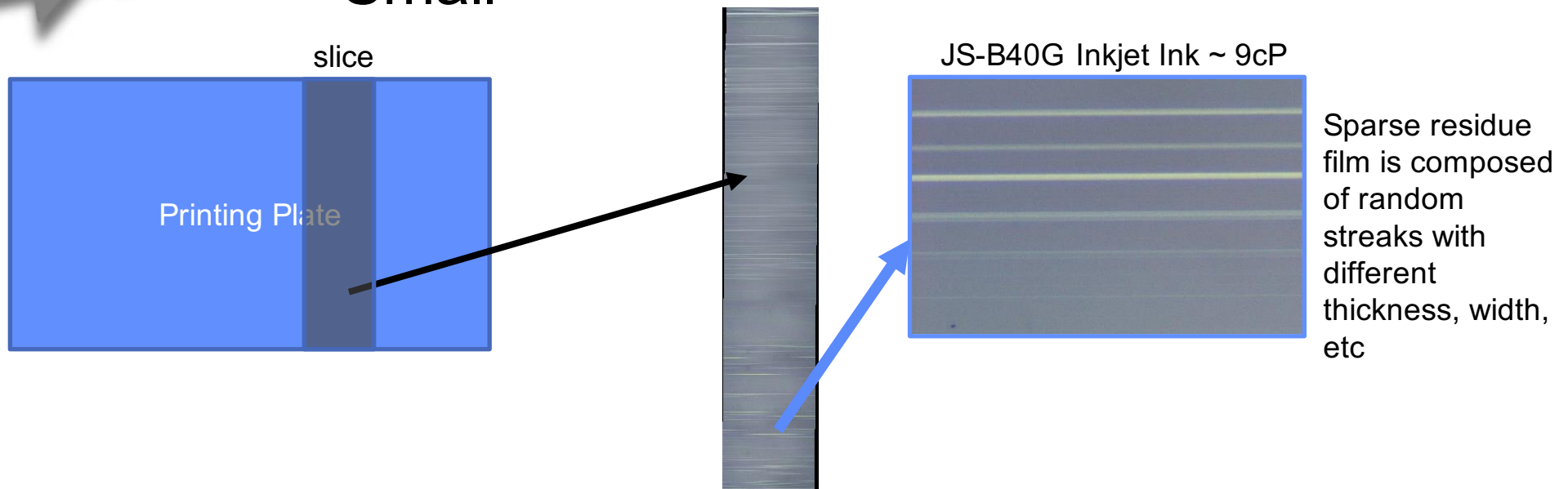
Show Doctor-blade call-out on gravure figure



Dragout is currently one of the largest challenges for gravure patterning precise mesoscale features (OTFTs, OLEDs, sensors)



# Wiping residue – Large particles vs. Small



Particles limit feature size and resolution.

- Particle size
- Wiping speed